

Notice of References Cited		Application/Control No. 10/552,728	Applicant(s)/Patent Under Reexamination FUJINO ET AL.	
		Examiner PAUL A. WARTALOWICZ	Art Unit 1793	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kreiskott, "Continuous electropolishing of Hastelloy substrates for ion beam assisted deposition of MgO. Superconductor science and technology, 16, 613-616, 2003
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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